

lectrodeposited Process and Mechanical Properties of Ni /Ni -P Bi-layered Coating

黃文杰、李弘彬、李得勝

E-mail: 374651@mail.dyu.edu.tw

ABSTRACT

Both pulse and direct current (DC) electroplating methods were employed in this thesis to prepare the Ni-P and Ni coatings, respectively. The former coating had low internal stress and high hardness while the latter possessed high toughness and better ductility. With these different characteristics, the internal stress of a Ni/Ni-P composite coating was tuned to a smaller magnitude by changing the thickness ratio between Ni and Ni-P layers. The microstructure examined by using transmission electron microscope (TEM) showed the Ni-P coating had a P-content of 10.7 wt% and a structure of equiaxed grains accompanying with scattered nanograins. The crystal defects, such as twins and dislocations, were observed in the microstructure. Furthermore, the electroplated Ni coating was with coarse columnar grains. Although the Young ' s modulus of the homogeneous coating was able to be determined by load-indentation curve of the nano-indentation testing, the apparent Young ' s modulus of the Ni/Ni-P composite coating was difficult to be measured directly. Therefore, a simple bending testing on a cantilevered specimen was designed in this study. The bending testing provided a tool for measuring the mechanical properties of multi-layered specimen. The good ductility of the electrodeposited Ni coating indicated its higher impact resistance while the high hardness of Ni-P coating revealed its low tolerance in deformation.

Keywords : Electroplating、multi-layer coating、nano-indentation、bending testing

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